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Abstract of the Disclosure

[0052] An interlocking lid which is suitable for a wet bench tank used in the processing of semiconductor wafer substrates. The interlocking lid includes a pair of lid panels typically provided with a clasp having elements for engaging and interlocking with each other when the lid panels are in a closed position. At least one of the lids may further include a beveled lid shoulder which facilitates runoff of liquids from and hinders pooling of liquids on the exterior surface of the lid.